

Docket No. . 1232-4421US1
U.S. Serial No. 09/664,715

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

Applicants: UEHARA et al.
Serial No.: 09/664,715
Filed : September 19, 2000
For : WAFER PROCESSING APPARATUS, WAFER PROCESSING METHOD, AND SEMICONDUCTOR SUBSTRATE FABRICATION METHOD

Group Art 1746
Examiner: Unknown

SUPPLEMENTAL TO SECOND INFORMATION DISCLOSURE STATEMENT

Commissioner for Patents
2900 Crystal Dr.
Arlington, VA 22202-3513

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NOV 30 2001

Sir:

TC 1700

Applicants submit this Supplemental To Second Information Disclosure Statement to correct typographical errors contained in the PTO-1449 form filed on September 21, 2001. Specifically, EP3257826, EP1304733 and EP 8316182 should be JP3-257826, JP1-304733 and JP 8-316182 respectively.

A new PTO-1449 form is attached herewith to replace the PTO-1449 form filed on
September 21, 2001. ^(paper no. 3) Copies of the references are not attached because they were submitted with the Second Information Disclosure Statement on September 21, 2001.

This document is being filed prior to a first Office Action. No fee is believed due by this filing.

The Commissioner is hereby authorized to charge any additional fees which may be

required for this Information Disclosure Statement, or credit any overpayment to Deposit

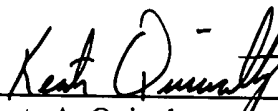
Account No. 13-4503, Order No. 1232-4421US1.

Respectfully submitted,

MORGAN & FINNEGAN, L.L.P.

Dated: November 29, 2001

By:



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